FIG.1 (PRIOR ART)

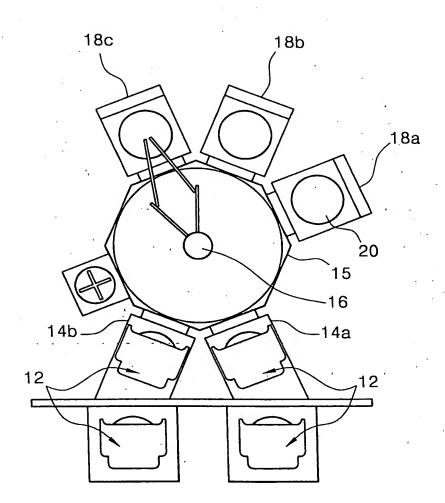
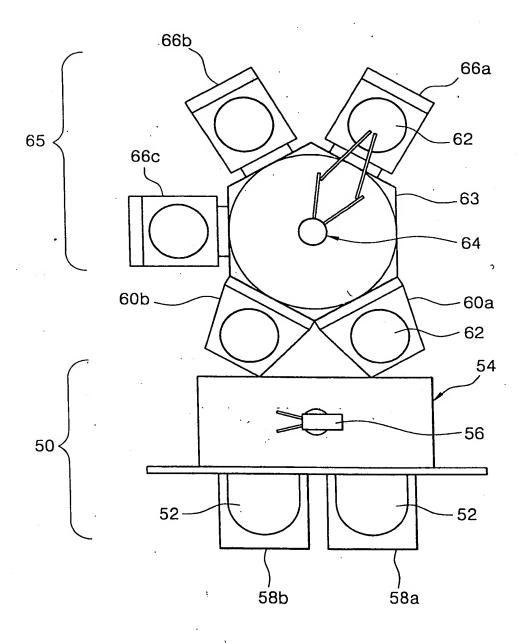
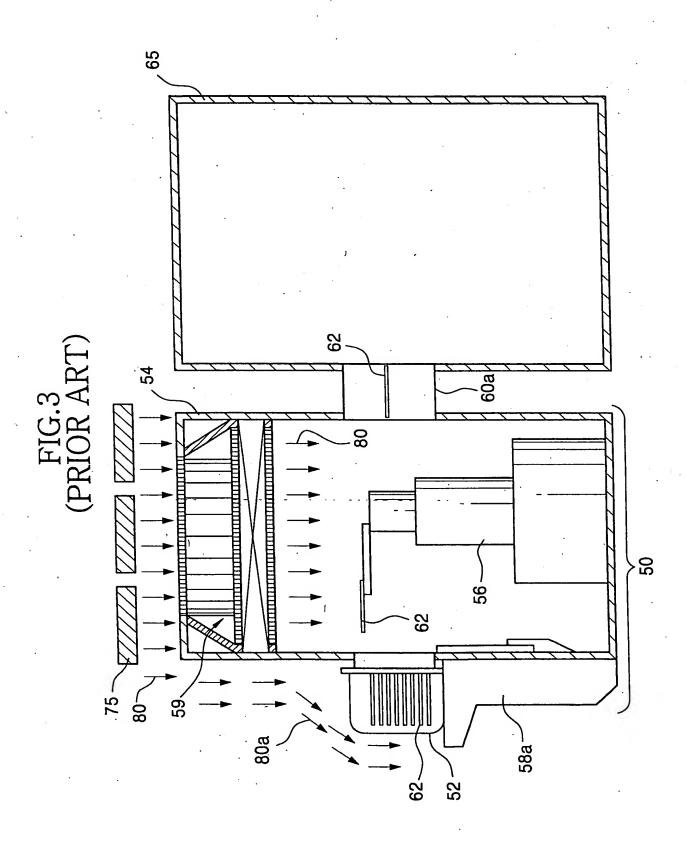


FIG.2 (PRIOR ART)





"Substrate Processing Apparatus And Method of Processing Substrate While Controlling For Contamination in Substrate Transfer Module"

Serial No. (New) - Attny. Doc. No. SEC.1087

Inventors: Yo-Han AHN et al.

FIG.4 (PRIOR ART)

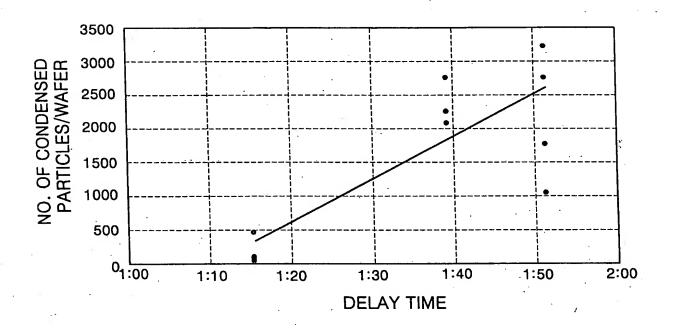


FIG.5

100

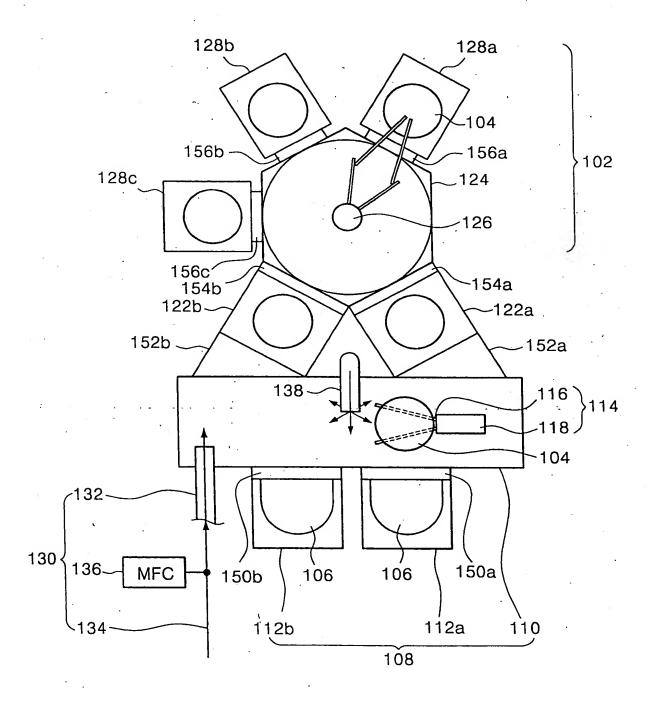
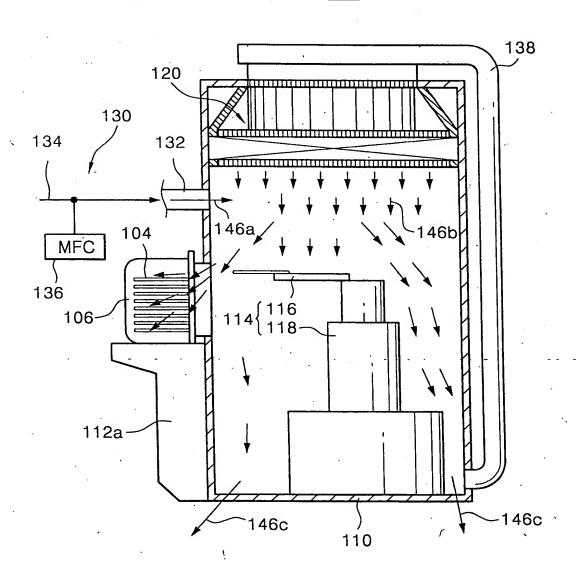


FIG.6

108





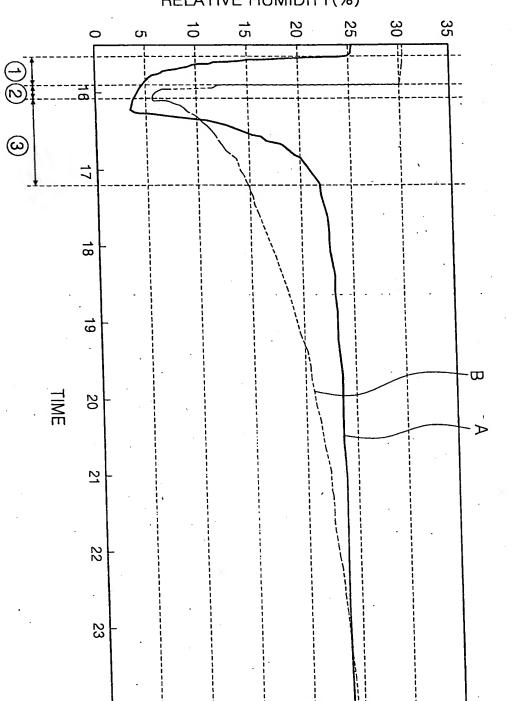


FIG.8

